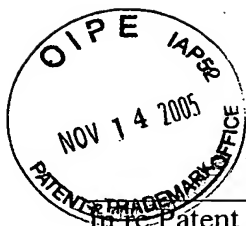


IFW



Docket No.: 8734.254.00-US
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Yun-Ho JUNG

Customer No.: 30827

Application No.: 10/705,891

Confirmation No.: 6104

Filed: November 13, 2003

Art Unit: 1756

For: MASK FOR LASER IRRADIATION AND
APPARATUS FOR LASER
CRYSTALLIZATION USING THE SAME

Examiner: Stephen D. Rosasco

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT

Dear Sir :

In response to the restriction requirement set forth in the Office Action mailed September 14, 2005, (Paper No. 20050907), Applicant hereby provisionally elects Group I, (Claims 1-24), for continued examination.

The Examiner has required restriction between Group I (Claims 1-24) and Group II (Claims 23-25).

An action on the merits of the claims relating to the above election and a Notice of Allowance thereof are respectfully requested.

Applicant hereby authorizes the Commissioner of Patents to charges any fees necessary to complete this filing, including any fees required under 37 C.F.R. §1.136 for any necessary Extension of Time to make the filing of the attached documents timely, or credit any overpayment in fees, to Deposit Account No. 50-0911. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. §1.136 for the necessary extension of time. Two copies of this sheet are enclosed.

Dated: November 14, 2005

Respectfully submitted,

By Valerie P. Hayes
Valerie P. Hayes
Registration No.: 53,005
McKenna Long & Aldridge LLP
1900 K Street N.W.
Washington, D.C. 20006
Voice: 202-496-7500
Fax: 202-496-7756
Attorneys for Applicant